What is claimed is:

1. A method of manufacturing an electron-emitting source, comprising the steps of:

forming a film containing curled nanotube fibers on a substrate; and

irradiating the film formed on the substrate with a laser beam perpendicularly to the substrate.

2. A method according to claim 1, wherein the step of forming includes the step of forming a film of the nanotube fibers made of carbon.

3. A method according to claim 1, wherein the step of forming includes the step of forming the film in accordance with any one scheme selected from electrodeposition, thermal CVD, and spraying.

4. A method according to claim 1, wherein the step of forming includes the step of forming the film on the substrate made of iron or an iron-containing alloy.

5. A method according to claim 1, wherein the step of irradiating includes the step of irradiating with the laser at an energy density of 5 mJ/cm^2 to 500 mJ/cm^2.

6. A method according to claim 1, wherein the step of irradiating includes the step of irradiating the film with an excimer laser as the laser.

7. A method according to claim 1, wherein the step of irradiating includes the step of irradiating the film with the laser in any one atmosphere selected from air, gas, and vacuum.